



SEMICONDUCTOR



GENERAL  
VACUUM



ANALYTICAL  
INSTRUMENTS



R&D



PHOTOVOLTAIC



LED



CHEMICAL  
INDUSTRY



EMT-MK

# THE COST REDUCER

For high throughput and highly efficient  
temperature management

THE EMT-MK has an integrated controller and a temperature management system. Reduce of material's outgassing with a compact size. Multiple interface options are available. Air or water cooling as requested.

## BENEFITS

- Ultra-high vacuum
- Integrated controller
- Installation in any orientation
- Safety standards
- Most energy efficient temperature management
- Water cooled (air cooling only on request)



| Models                           | EMT1700MK | EMT2200MK | EMT3300MK | EMT3800MK | EMT4200MK |
|----------------------------------|-----------|-----------|-----------|-----------|-----------|
| Pumping speed in l/s             | 1,650     | 2,200     | 3,300     | 3,600     | 4,200     |
| Ultimate pressure Pa             | < 2,00E-7 | < 2,00E-7 | < 2,00E-7 | < 5,00E-7 | < 5,00E-7 |
| Backing pump (recommended) l/min | > 2,000   |           |           |           |           |
| Inlet flange diameter DN         | DN200     | DN250     | DN320     | DN320     | DN350     |
| Throughput N2 (sccm)             | 4400      | 4400      | 2100      | 2800      | 2800      |
| Start up time (min)              | < 10      | < 10      | < 11      | < 12      | < 12      |
| Stop time (min)                  | < 10      | < 10      | < 11      | < 12      | < 12      |
| Height in mm                     | 501.5     | 446.5     | 445       | 501       | 444       |
| Size in mm (diameter)            | Ø340      | Ø340      | Ø380      | Ø415      | Ø415      |
| Weight in kg (Standard)          | 65        | 62        | 70        | 80        | 75        |

All data without guarantee.

## APPLICATIONS FOR EMT-MK

EUV lithography (extreme ultra violet)

Micro-machining (MEMS)

CD line width measurement

SEM/TEM Electron

Microscopy

XPS

Nano technology

Ion plating

Sputtering

Etching

CVD

**For further information, technical data or drawings please contact**  [components@ebara-pm.eu](mailto:components@ebara-pm.eu)

EBARA is a worldwide leading global manufacturer of vacuum and semiconductor systems used in the production of wafers, liquid crystals, solar cells and other products requiring advanced technology.

EBARA supports



EBARA Precision Machinery Europe (EPME) is part of the Japanese EBARA Group and employs more than 170 people in Europe. The portfolio includes dry and turbo molecular vacuum pumps as well as gas abatement systems. In addition, EPME sells state-of-the-art CMP tools, wafer bevel polishing and substrate coating systems. In Europe, EPME has a central warehouse and two overhaul centres for vacuum pumps. EBARA is No 2 on the world market for CMP tools and vacuum pumps.

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